

IN THE CLAIMS

Kindly **REPLACE** claims 1 and 9 with the following:

1. A silicon refining method comprising the steps of:
 - filling an unlined inductive crucible (1) with solid silicon;
 - melting the content of the crucible;
 - creating, by means of the inductive crucible, a turbulent stirring of the silicon melt (b) by bringing the liquid from the bottom of the crucible to the free surface by ascending along the central axis of the crucible; and
 - directing a plasma (f) generating by an inductive plasma torch (2) towards the melt surface for a duration enabling elimination of impurities for which the reactive gas (g_r) of the plasma is adapted.

9. A silicon refining installation comprising:
 - an unlined inductive crucible (1) adapted to receiving the silicon;
 - an inductive plasma torch (2) directed towards the free surface of the silicon load contained in the crucible; and
 - a removable magnetic yoke (3) between the plasma torch (2) and the crucible (1) for inverting a stirring direction of the silicon load, the yoke being ring-shaped to enable the passing of the plasma flame (f).